N THE UNITED STATES PATENT AND TRADEMARK OFFICE application of

Allan Rosencwaig et al.

Application No.: 10/717,316

Filed: November 19, 2003

For: OPTICAL INSPECTION EQUIPMENT FOR SEMICONDUCTOR WAFERS

WITH PRECLEANING

Confirmation No.: 8272

Group Art Unit: 2877

Examiner: R.M. Punnoose

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

353 Sacramento Street, Suite 2200 San Francisco, CA 94111 (415) 772-4900

M/S RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 **CERTIFICATE OF MAILING** 

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on August 2

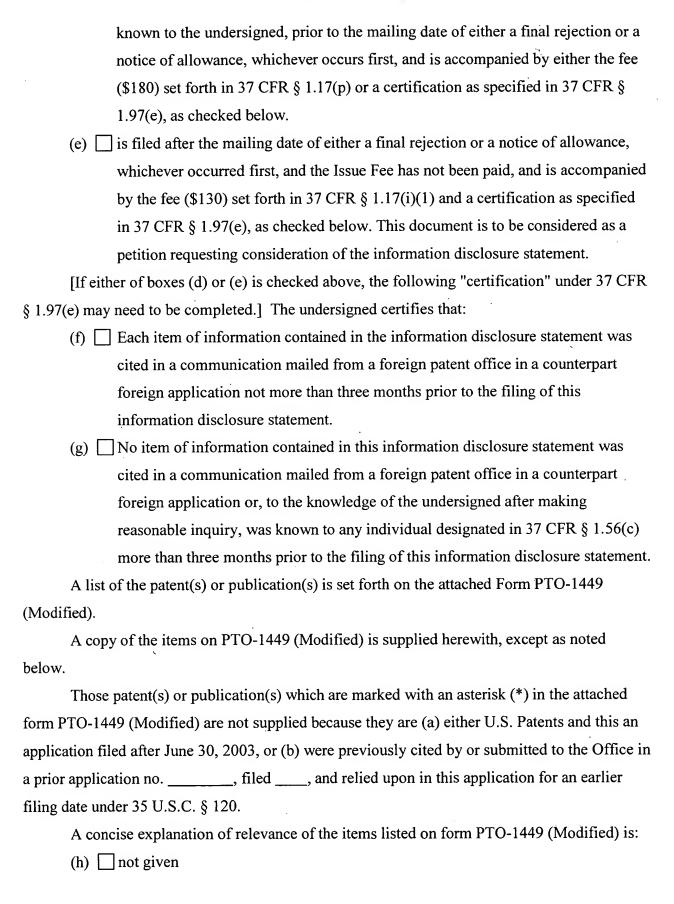
STALLMAN & POLLOCK LLP

Sir:

Applicant(s) submit(s) herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which they are aware, which they believe(s) may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

- (a) accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).
- (b) is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.
- (c) \( \) as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits, or before a first office action after filing a Request for Continued Examination under §1.114.
- (d) is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is



(i) 🔲	given for each listed item
(j) 🛭	given for only non-English language listed item(s) [Required]
(k) 🗌	is in the form of an English language copy of a Search Report from a foreign
	patent office, issued in a counterpart application, which refers to the relevant
	portions of the references [copy attached].

With respect to Japanese Patent No. 10-137704, the following information is derived from a DIALOG search:

"Semiconductor cleaning method using microwave excitation--involves reducing surface tension of cleaning liquid and cleaning substrate, by microwave irradiation.

The method involves immersing a silicon substrate (6) in a cleaning liquid (4) contained in a washing tank (3) made of quartz. A microwave with frequency range of 0.4-25GHz is irradiated on the cleaning liquid. By microwave irradiation, the surface tension of cleaning liquid is reduced and the substrate is cleaned.

ADVANTAGE - Removes contamination adhering to inner portions of holes, effectively. Offers high precision of cleaning. Produces high quality substrate."

The Examiner is reminded that a "concise explanation of the relevance" of the submitted items "may be nothing more than identification of the particular figure or paragraph of the patent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

The Commissioner is hereby authorized to charge our Deposit Account No. 50-1703, under Order No. TWI-8520, for any fees required in connection with the filing of this

Information Disclosure Statement. A duplicate copy of this Notice is enclosed for this purpose. In particular, in the event that an Office Action has crossed in the mail with this Information Disclosure Statement, the Commissioner is authorized to charge the above-named deposit account for any fees required pursuant to CFR §§ 1.17(p) or 1.17(i)(1).

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: August 2, 2004

Michael A. Stallman Reg. No. 29,444

Attorneys for Applicant(s)

# INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)

Docket Number (Optional) TWI-8520	Application Number 10/717,316		
Applicant(s)			
Allan Rosencwaig et al.			
Filing Date	Group Art Unit		
November 10, 2002	2977		

### **U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	Ref	DOCUMENT NUMBER	DATE	Name	CLASS SUBCLASS		FILING DATE	

### FOREIGN PATENT DOCUMENTS

-		DOCUMENT					TRANSLATION	
•	REF	NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	No
	BA	WO 95/00681	01/05/1995	PCT	C23G	1/00		
	BB	10-137704	11/08/1996	Japan (see Dialog Abstract in IDS text)	B08B	3/12		
	BC	WO 98/05066	02/05/1998	PCT	H01L	21/66		
	BD	WO 99/35677	07/15/1999	PCT	H01L	21/306		
	BE	4-357836	12/10/1999	Japan	H01L	21/304	Translation	

OTHER DOCUMENTS
(Including Author, Title, Date, Pertinent Pages, Etc.)

BF	K. Imen et al., "Laser-assisted micron scale particle removal, "App. Phys. Lett., Vol. 58, No. 2, 14 January 1991, pp. 203-205.

	Examiner	Date Considered				
Ì	Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if					
ı	not in conformance and not considered. Include copy of this form with next communication to applicant.					